



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

By application of

MONA M. EISSL

Serial No. 10/621,879 (TI-28394.1)

Filed July 17, 2003

For: EFFECTIVE SOLUTION AND PROCESS TO WET-ETCH
METAL-ALLOY FILMS I SEMICONDUCTOR PROCESSING

Art Unit 1765

Examiner Kin-Chan Chen

Customer No. 23494

Mail Stop Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

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AMENDMENT UNDER 37 C.F.R. 1.116

In response to the Office action dated June 13, 2006, the following remarks are presented: